

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Branco et al.

Serial No.: 09/617,454

Filed: July 17, 2000

Title: Method for Cleaning Plasma Etch  
Chamber Structures

Attorney Docket No.: CY-0015



Group Art Unit: 1746

Examiner: Smetana, Jiri F.

4/A  
SH  
4/29/02

RESPONSE TO OFFICE ACTION

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

The following is submitted in response to the Office Action dated December 6, 2001, and is currently due April 6, 2002, with a one month extension.

Entry of the following amendments is respectfully requested.

RECEIVED  
APR 19 2002  
TC 1700

37 C.F.R. §1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:  
Assistant Commissioner for Patents, Washington, D.C. 20231.

Date of Deposit: APRIL 8, 2002

Typed Name: BRADLEY T. SAKO

Signature: *Bradley T. Sako*